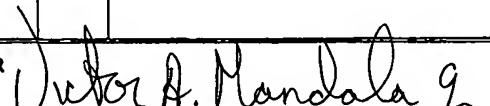


<p>INFORMATION DISCLOSURE CITATION (Use several sheets if necessary)</p> <p><b>MAY 26 2004</b></p> <p><b>PTO-146 (2-04)</b></p>		Docket Number (Optional) <b>FUJI:200A</b>		SERIAL NO.: <b>10/646,590</b>				
		APPLICANT(s) <b>Takashi KOBAYASHI et al.</b>						
		FILING DATE: <b>August 22, 2003</b>			Group Art Unit <b>2826</b>			
<b>U.S. PATENT DOCUMENTS</b>								
EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
VAMJ	US	4,602,266 A	7/86	Coe	357	20		
VAMJ	US	5,345,101 A	6/94	Tu	257	495		
<b>FOREIGN PATENT DOCUMENTS</b>								
	REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES      NO	
VAMJ	GB	1427014 A	3/76	GB				
<b>OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)</b>								
EXAMINER <i>Victor A. Mandala</i>		DATE CONSIDERED <i>9-1-04</i>						

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

<b>INFORMATION DISCLOSURE CITATION</b> <small>(Use several sheets if necessary)</small>				Docket Number (Optional)	Application Number			
				FUJI:200A		10/646,590		
				Applicant(s)		Takashi KOBAYASHI et al.		
				Filing Date	August 22, 2003			Group Art Unit
U.S. PATENT DOCUMENTS								
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE		
VAMJ	US 4,412,242	10/83	Herman et al.	357	52			
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FOREIGN PATENT DOCUMENTS								
REF	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation		
						YES	NO	
VAMJ	EP 0 671 769 A2	9/95	EPO					
	EP 0 749 163 A2	12/96	EPO					
	EP 0 115 093 A2	8/84	EPO					
	GB 2 161 649 A	1/86	GB					
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)								
VAMJ	"Optimization and Surface Charge Sensitivity of High-Voltage Blocking Structures with Shallow Junctions"; Hamza Yilmaz; July 1991; IEEE Transactions on Electron Devices, Vol. 38, No. 7; pages 1666-1675.							
VAMJ	"A Parametric Study of Power Mosfets"; Chenming Hu; Proceedings of the Conference of Rec. Power Electronics Specialists, 1979 IEEE; pages 385-395.							
EXAMINER			DATE CONSIDERED	9-1-04				
EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								